

THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Yoshiro SHIOKAWA et al.

Group Art Unit: 2881

Application No.:

10/024,243

Examiner:

P. JOHNSTON

Filed: December 21, 2001

Docket No.: 111522

For:

METHOD AND APPARATUS FOR ION ATTACHMENT MASS SPECTROMETRY

REQUEST FOR RECONSIDERATION

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In reply to the March 22, 2005 Office Action, reconsideration is requested in light of the following remarks.

Claims 1-8 are pending. Reconsideration in view of the following remarks is respectfully requested.

I. The Claims Define Patentable Subject Matter

Claims 1, 2, 5 and 6 are rejected under 35 U.S.C. §102(b) as anticipated by U.S. Patent No. 4,948,962 to Mitsui; and claims 3, 4 and 7-10 are rejected under 35 U.S.C. §103(a) as unpatentable over Mitsui in view of U.S. Patent No. 6,744,041 to Sheehan. These rejections are respectfully traversed.

A significant feature of the present invention is that in the ion attachment mass spectrometry (IAMS), an error measurement caused by the interference peaks is improved. Further, the only object to be essentially measured is accurately measured in a separated state